



AF
ITW

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail, in an envelope addressed to: MS Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below.

Dated: July 1, 2005

Signature: _____

(Michael R. Hull)

Docket No.: 30205/38081A
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Jae H. Kim et al.

Application No.: 10/719,135

Confirmation No.: 2226

Filed: November 21, 2003

Art Unit: 1755

For: Chemical Mechanical Polishing Slurry for
Ruthenium Titanium Nitride and Polishing
Process Using the Same

Examiner: Michael A. Marcheschi

AMENDMENT IN RESPONSE TO FINAL OFFICE ACTION
(37 C.F.R. §1.116)

MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the final Office Action dated May 4, 2005, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.